



NEUTRONIX / QUINTEL

685A Jarvis Drive, Morgan Hill, CA 95037 Ph: (408)776-5190 Fax: (408)776-1039

Q 4000-4 MASK ALIGNER

The NXQ 4000-4 Mask Aligner combines innovative design with precision alignment and exposure features.

It supports both vacuum and contact printing and handles partial and whole substrates up to 100mm (4") diameter.

The versatility of the NXQ 4000-4 has made it the choice of manufacturing facilities, R&D Centers and University programs around the world, for a wide range of technologies.





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Features

- Substrate sizes from pieces to 100mm (4") diameter (6" diameter with 4k6 configuration)
- Manual X-Y joystick and micrometer theta alignment stage
- Easy manual tray-load for substrate loading / unloading
- Vacuum / Pressure contact exposure modes
- VariView splitfield/ singlefield microscope with zoom feature (CCTV viewing optional)
- Simple topside mask loading
- Vari-Watt constant power UV power supply
- UV Collimation lens for improved printing resolution → Shock Isolation table included as standard
- Easy operation- ideal for multi-user labs
- Low maintenance

Options

- Infrared (IR) backside alignment
- NUV Hg (280-350nm) exposure optics
- Carousel (2 chuck) loading - up to 4" wafers
- Manual micrometer for X-Y alignment
- CCTV option for MagnaView microscope
- Pulsed exposure timer sequencing

Performance

Print Modes

- Soft, Pressure or Vacuum modes

Print Resolution <1.0 microns*
(with vacuum contact-)

Substrate size from pieces, up to 100mm



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Alignment Stage

- Alignment Travel X-Y
 - Alignment Travel Theta
 - Stage Scan
 - X-Y Movement
 - Theta Rotation Range
 - Z Axis Shiftage
 - Mask/ Wafer separation
 - Mask Size
 - Topside Alignment overlay*
 - Backside IR Alignment Overlay*
- * Operator/ process dependant

Manual Joystick
Manual Micrometer
+/- 16 mm
+/- 3.8mm
+/- 7 degrees
< 0.05 microns
0 – 180 microns
2.5x2.5" up to 5x5"
<=1.0 microns
>2 microns

Electronics

- Programming & Control

PLC with LCD Display.
Intuitive operator Interface for
menu driven operation

UV Lamphouse/ UV Exposure Optics

- UV Lamphouse
- Exposure Optics
- UV Uniformity

200/350W
UV (350-450 nm) standard
+/- 3%, 4" diameter field

System Requirements

- Voltage
- Compressed Air
- Vacuum
- Nitrogen (or CDA)

110VAC./60 Hz or 240VAC 50Hz
5.4 bar (80 PSI)
-0.7 bar (21" Hg)
3 bar (40 PSI)

System / Module Data

- W x D x H
- Weight

48" x 36" x 50"
217Kg (480 Lb)

www.acrosemi.com



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